



ATENT APPLICATION

RC/13723

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Date November 20, 2002

In re the Application of

Makoto KOBAYASHI et al.

Group Art Unit: 3723

Application No.: 09/830,434

Examiner: H. Shakeri

Filed: April 26, 2001

Docket No.: 109352

For: POLISHING PAD AND POLISHING METHOD FOR SEMICONDUCTOR WAFER

**PETITION FOR EXTENSION OF TIME UNDER 37 C.F.R. §1.136(a)  
AND TRANSMITTAL OF FEE UNDER 37 C.F.R. §1.17**

Director of the U.S. Patent and Trademark Office  
Washington, D.C. 20231

Sir:

Transmitted herewith is a Continuing Application based on the above-identified patent application. The shortened statutory period for response having expired on October 26, 2002, an extension of time for a period of one month is hereby requested. Attached hereto is our Check No. 136398 in the amount of \$110 pursuant to 37 CFR §1.17.

The Director is hereby authorized to charge any additional fee (or credit any overpayment) associated with this communication to Deposit Account No. 15-0461. Two copies of this petition are enclosed.

Respectfully submitted,

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